



APPLICATION DATA SHEET

Electronic Version v14.0

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Title of Invention	ELECTRON DIFFRACTION SYSTEM FOR USE IN PRODUCTION ENVIRONMENT AND FOR HIGH PRESSURE DEPOSITION TECHNIQUES		
Application Type: regular, utility Attorney Docket Number: B1180/20019			
Correspondence address: Customer Number: 03000 *03000*			
Priority Data: Doc.No: 02020889.8; Country - EP; Date: 2002-09-18 us-priority-claimed			
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